
OLIFF & BERRIDGE, PLC

ATTORNEYS AT LAW

Application Data Sheet**Application Information**

Application Type:: Regular
Subject Matter:: Utility
CD-ROM or CD-R:: None
Title:: METHOD FOR EVALUATING LITHOGRAPHY SYSTEM, METHOD FOR ADJUSTING SUBSTRATE-PROCESSING APPARATUS, LITHOGRAPHY SYSTEM, AND EXPOSURE APPARATUS
Attorney Docket Number:: 109325.01
Suggested Drawing Figure::
Total Drawing Sheets:: 10
Small Entity:: No

Applicant Information

Applicant Authority type:: Inventor
Primary Citizenship Country:: Japan
Status:: Full Capacity
Given Name:: Yuji
Middle Name::
Family Name:: IMAI
Name Suffix::
City of Residence:: Saitama
State or Province of Residence::
Country of Residence:: Japan

Correspondence Information

Correspondence Customer Number:: 25944

Domestic Priority Information			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	Division of	09/839,202	04/23/01
Foreign Priority Information			
Country::	Application Number::	Filing Date::	Priority Claimed::
Japan	2000-124506	04/25/00	Yes
Assignee Information			
Assignee Name::	NIKON CORPORATION		
Street of mailing address::	2-3, Marunouchi 3-chome		
	Chiyoda-ku		
City of mailing address::	Tokyo		
State or Province of mailing address::			
Country of mailing address::	Japan		
Postal or Zip Code of mailing address::	100-8331		